

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Robert Bristol et al.

Group Art Unit:

Serial No.:

10/679,816

Examiner:

Filed:

October 6, 2003

For:

**Enhancing Photoresist Performance** 

Using Electric Fields

Atty. Dkt. No.:

ITL.1023US (P16710)

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

## <u>INFORMATION DISCLOSURE STATEMENT</u>

Dear Sir:

Applicant submits the references listed on the attached form PTO 1449 together with any required copies of such references.

This statement is being filed within three months of the filing date of the application. Please apply any charges or credits to Deposit Account No. 20-1504 (ITL.1023US).

Respectfully submitted,

Date: 4

mothy M. Trop, Registration No. 28,994

PROP, PRUNER & HU, P.C. 8554 Katy Freeway, Suite 100

Houston, Texas 77024 (713) 468-8880 [Phone]

(713) 468-8883 [Fax]

Date of Deposit: December 30, 2003

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA

Sherry Tipton

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